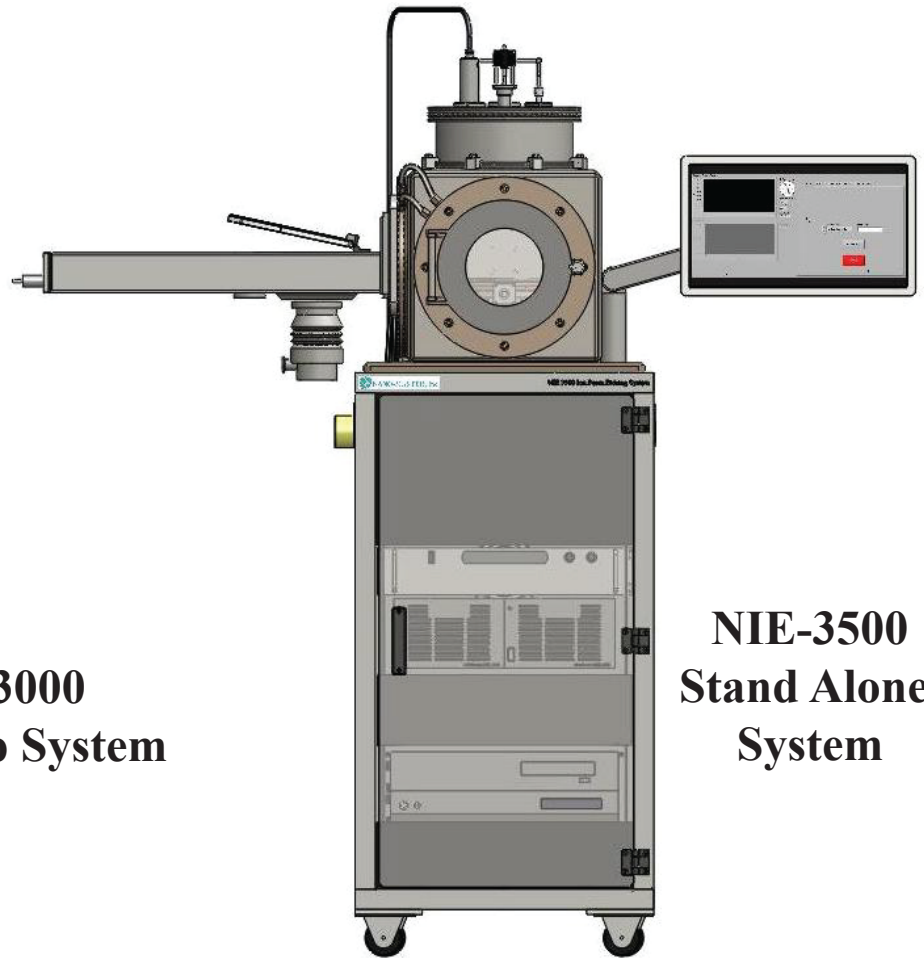


NANO-MASTER Ion Beam Milling/Etching Systems



**NIE-3000
Table Top System**



**NIE-3500
Stand Alone
System**

Features:

- Low Cost
- Ion Beam: Up to 2KV/10mA
- Ion Current Density 100-360 $\mu\text{A}/\text{cm}^2$
- Ion Beam Size: 4", 5", 6"
- Compatible with Reactive and Non-Reactive Gases (Ar, O₂, CF₄, Cl₂)
- Base Pressure 5×10^{-7} Torr
- 260 l/sec Corrosive Turbo Pump with 500 l/min Dry Scroll Pump
- 14" SS or Al Chambers
- Water Cooled Rotating/Tilted Platen (NIE-3500)
- Auto Load and Unload (NIE-3500)
- PC Controlled with LabVIEW Software
- Footprint 30"x30"

Applications:

- Surface Cleaning
- Surface Treatment
- Ion Beam Milling
- Ion Beam Etching with Reactive Gases:
 - Grating
 - Deep Trenches on SiO₂, Si and metals



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